

Lecture 6: Process Modules II

- **Announcements:**
- HW#1 due next Wednesday
- Module 4 online
- Video for Lecture 4 (the make-up lecture) online
 - ↳ I gave the username and password in class
 - ↳ Come and see me if you missed this
- TA Office Hours next week will be in the Moore Room of Cory Hall (in the courtyard)
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- **Today:**
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6
 - ↳ Example MEMS fabrication processes
 - ↳ Oxidation
 - ↳ Film Deposition
 - Evaporation
 - Sputter deposition
 - Chemical vapor deposition (CVD)
 - Plasma enhanced chemical vapor deposition (PECVD)
 - Epitaxy
 - Atomic layer deposition (ALD)
 - Electroplating
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 4, 5
 - ↳ Lithography
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- **Last Time:** going through Module 3
- Continue doing this ...
- ... then start Module 4